

DTU



# Agenda for TechForum 2023#1

- **Misc. Updates**
- **Energy Savings**
- **Lab expansions**
- **Facility projects and closures**
- **New equipment**



# Impact of DTU's Economical Situation

- All DTU entities have been "asked" to improve their finances
- We are not able to provide same or better services across all technology areas with less resources

**A decision was made not cut all things a bit but to look after actual usage and cut idle technology areas that only use resources (time, money, space)**

Gone through numbers and usage logs in Labmanager

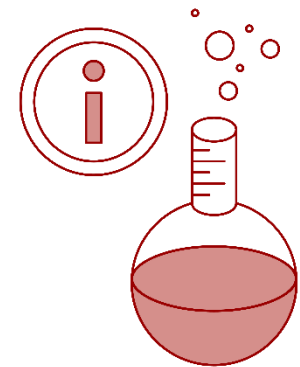
- Injection molding and electroplating took up more service hours than usage hours the last years
- We will discontinue to offer services regarding injection molding and electroplating
- We will try to find alternatives for those who have planned to use these technologies in the near future.
- We are working on moving the injection molder to DTU Construct, B427

**It is strongly advised to consult us if you plan a major research initiative on technologies offered by Nanolab.**

# MISC. UPDATES

# Bringing samples into the Cleanroom

- Please avoid!
  - Every sample taken in from the outside means increased risk of contamination of cleanroom or tools.
  - Samples just to be characterized will in general not be accepted
- Not previously approved materials/process:
  - write APV (find template in kemibrug)
  - in doubt ask Majken Becker
- Formalized procedure:
  - Get request form
    - find under “Cleaning Bench” in LabManager or send an e-mail to [training@nanolab.dtu.dk](mailto:training@nanolab.dtu.dk)
  - Fill in form, include process flow description and return to
    - [training@nanolab.dtu.dk](mailto:training@nanolab.dtu.dk) or
    - [jehan@dtu.dk](mailto:jehan@dtu.dk)
  - Wait for reply



# 3-weeks courses, summerschools etc.


- Plan in good time - NOW!
- Follow the guidelines given in
  - <https://www.nanolab.dtu.dk/About-DTU-Nanolab/FAQ/3weekCourse>
- Please spread this information to colleagues and “Institutstudienævn“

**Planning 3 week courses/Summer schools using the DTU Nanolab Cleanroom**

In order to have access to and use the cleanroom there are a number of conditions you have to meet:

- You have to register all 3 weeks/Summer school related cleanroom activities before we can give access.
- We should receive the registration at least 2 month before the start of the course
- Registration should include information about
  - Expected number of people and
  - Desired entry time and dates.
  - Equipment and chemical processes to be used (you have to book the tools yourself)
  - Name of teaching instructors.
  - Course responsible and
  - Course name/number
  - Which DTU Institute to use as organization in LabManager (which will be charged for any materials used)
- All Teaching Instructors should be experienced cleanroom users and have all the needed equipment training authorization. We cannot offer any help from our staff.
- The course students should always be accompanied by the instructor
- The students are not allowed to work with any chemicals (but can watch the instructor doing so from a safe distance).
- The students may operate equipment but only under strict supervision by the instructor and after demonstration by the instructor.
- You should make an agreement with our safety trainers to help the students through gowning at the first entry to the CR.
- All course participants should take the online intro course for 3-week courses well in advance and at least 3 working days before first access date. They should register **on our homepage**

**Sign up for the introduction course**



Sign up:

- If you are a DTU student
- If you are a DTU employee
- If you are a 3 week student
- If you are from outside DTU

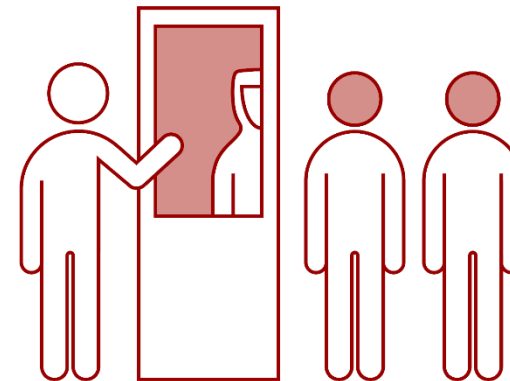
We need at least 1-2 working days to complete registration.

# Nanolab temporary moving out of building 347

Moving out to give room for establishing the PolyFabLab.

- Packlab closed
  - Ball bonder, Tabletop SEM and Dektak 150 will move to building 451 room 913
  - Other equipment in storage
- Computers for E-beam and Stepper lithography preparation:
  - Now located in building 346 room 055 ground floor

- People:
  - Detailed information will be found at the end of this presentation



# ENERGY SAVINGS

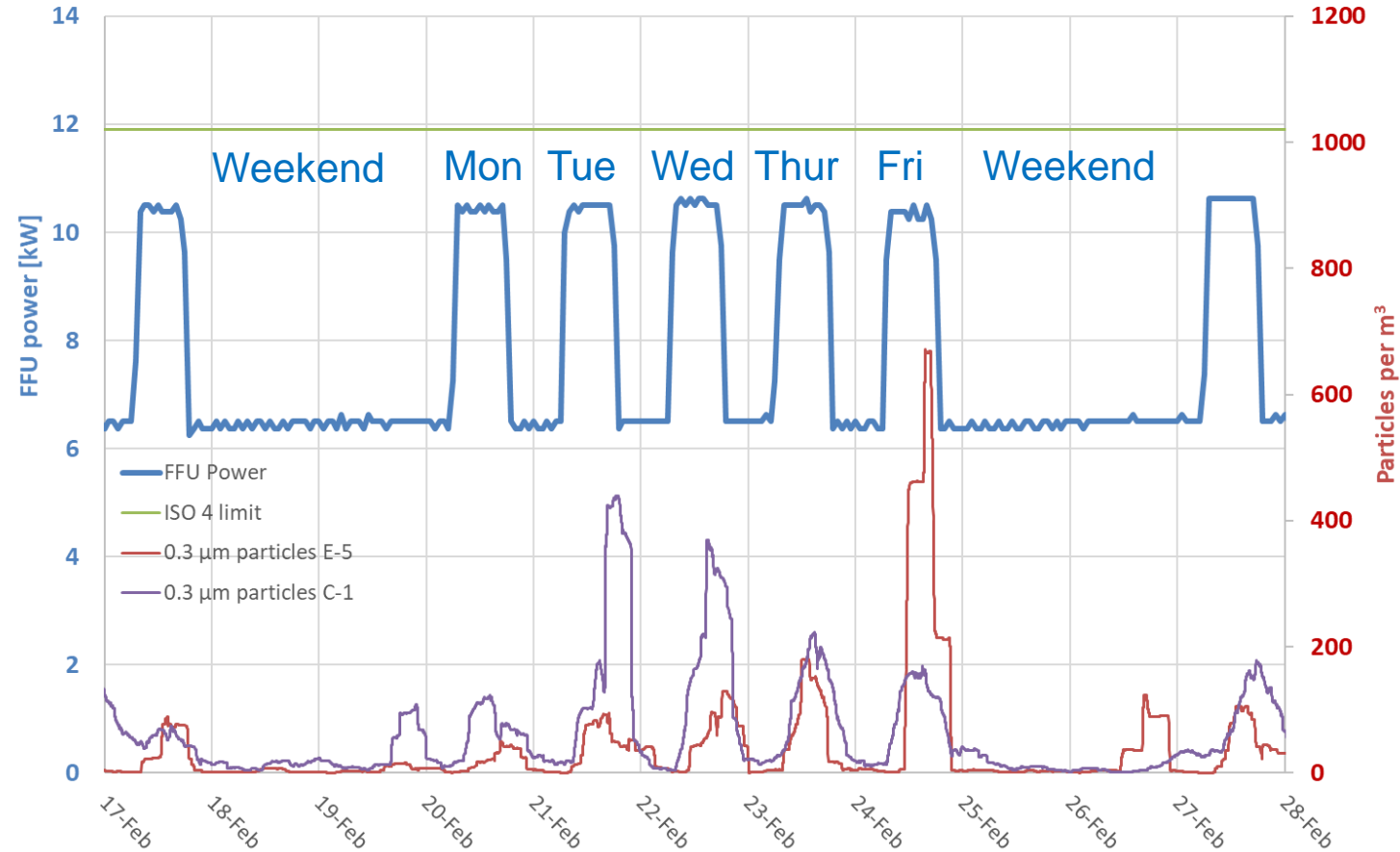


# Implemented energy savings - facility

- **Implemented savings: > 400.000 kWh/yr (> 10%)**

- Cleanroom light
  - From fluorescent to LED light
  - Switch off LED light when no one inside
  - Intelligent power-up via PIR sensors
- Old cleanroom (sections A, B and C)
  - Reduced air recirc. 18:00 to 06:00 + weekends
  - Better control of room overpressure (15-25 Pa)
- New cleanroom (sections D, E and F)
  - Ramp FFUs from 35% to 30% (507 to 435 rpm)
  - 18:00 to 06:00 + weekends
  - E-beam room and stepper not affected
- Measured impact:
  - Particles appear not a big issue
  - Room temperature on target
  - Air flow change has impacted one sensitive tool

Air recirculation rampdown



# Energy Savings – Equipment (so far)

## **Furnaces (power + nitrogen savings)**

Standby Temperature reduced from 700 to 400 °C:

**A1 (B-Drive), A2 (Gate), A3 (P-Drive), C3 (Anneal-Bond)**

## **Pumps (power + nitrogen savings)**

Loadlock pumps turned off when not in use: **Metal-ICP, III-V ICP**

## **Chillers (power + nitrogen savings)**

Stand-by temp @ 20 °C - reduce both power and nitrogen consumption: **AOE**

## **Low-use systems turned off (power + nitrogen savings)**

Request turn-on or get trained: **III-V RIE, Thermal Evaporator**

**more to come...**

# LAB EXPANSIONS

# PolyFabLab in B347:



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**DTU – LLYN.347**  
**Indretning af nyt PolyFabLab**  
**samt kontor, møde- og køkkenfaciliteter**

Udarbejdet af H+ A/S | MOE A/S | CHRISTOPHER PERRY

# PolyFabLab (B347) time line – very loose

- 8 March 2023: People move out (see next slides for new office locations)
- 13 & 15 March: Packlab moves (partially) to B451. Some tools warehoused.
- 17 March: Beamer, Prolith servers will have moved to B346, room 055
- End March: Contractors take over B347
- Ca. Q1 2024: Project complete
- Q1 2024: People move back to B347
- Q2 2024: installation of tools in PolyFabLab

***“Invite the curious and innovative to explore and exploit nanofabrication”***



**346A – Nanolab Phase 4**

# Situation for Nanolab Phase 4

- Cleanroom and structural design has been tendered
- Standstill until March 21<sup>st</sup> 2023
  - then contract can be signed
- Plan to open in 2026

## Design goals

- Mission-critical facility
- Technology at the forefront
- Open and inspiring building
- EMI and vibration sensitivity
- Deep sub-fab for 200 mm toolsets
- Full ISO 4 possibility – ISO 4 to 6 initially
- Total area in excess of 4000 m<sup>2</sup>
- At least 700 m<sup>2</sup> cleanroom under filter
- Budget of 345 Mkr (2020 kr)





Concept drawing – do not  
take too literally!





Concept drawing – do not  
take too literally!



Concept drawing basement column  
forrest – do not take too literally!



Concept drawing – do not  
take too literally!

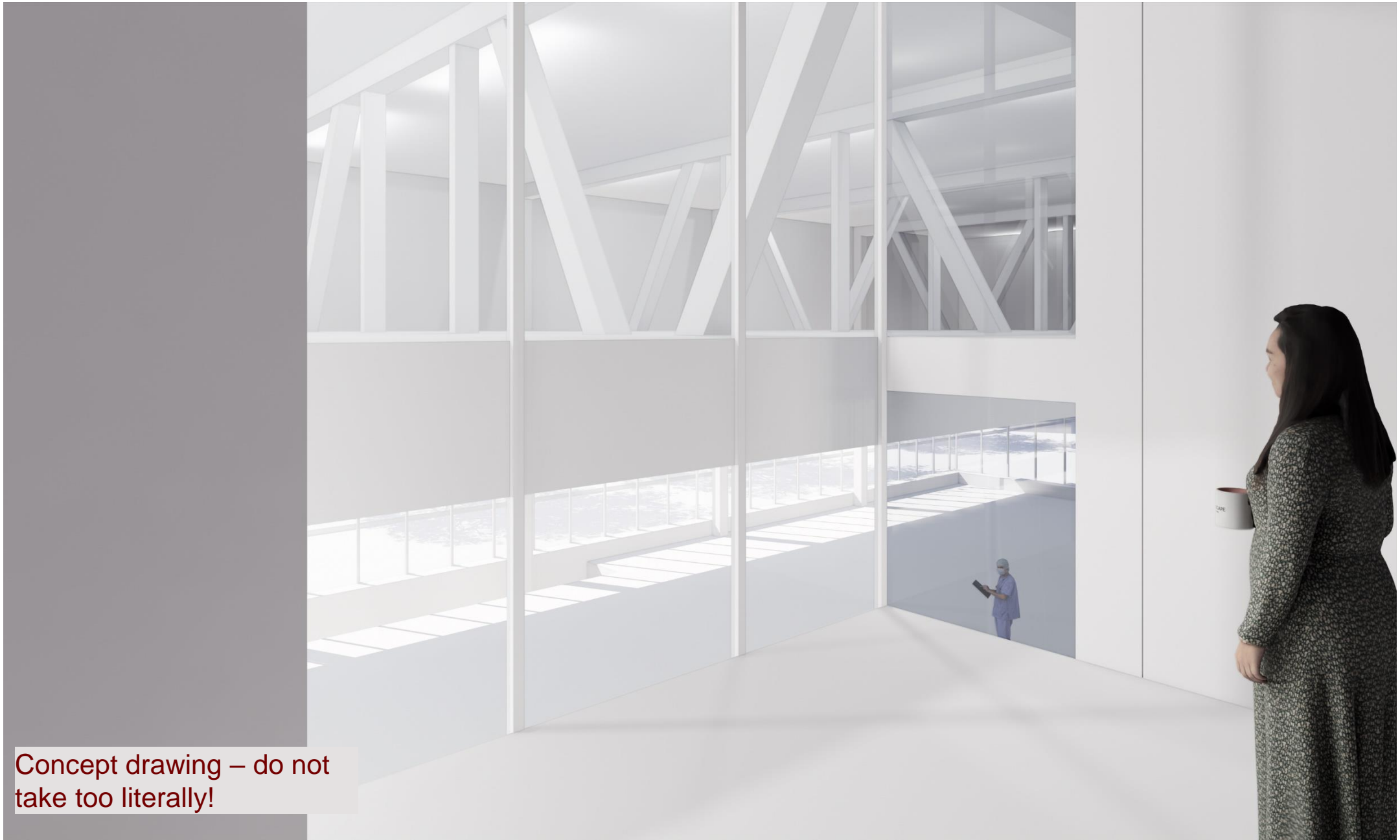


Concept drawing – do not take too literally!



Concept drawing – do not take too literally!





Concept drawing – do not take too literally!



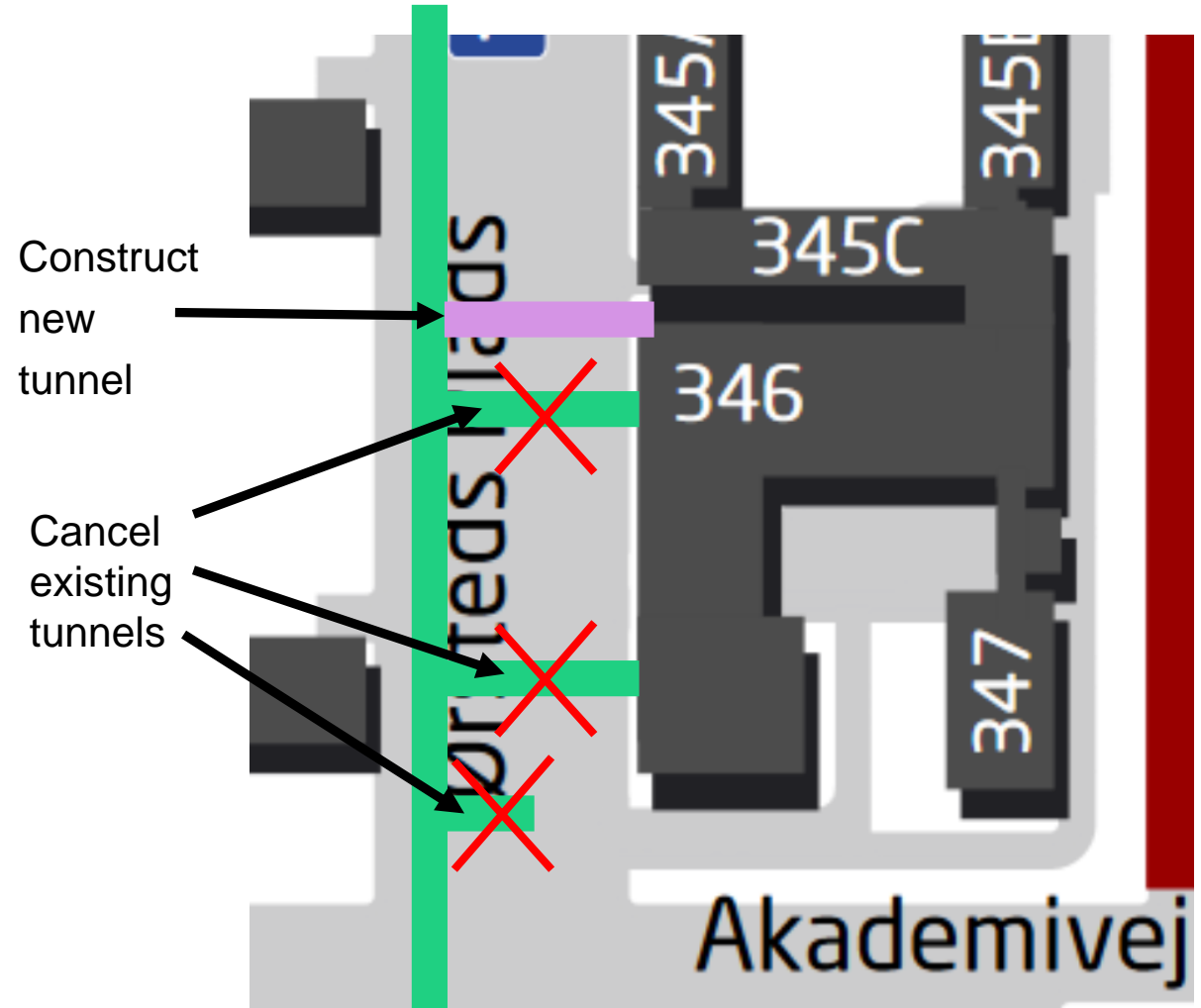
Concept drawing – do not  
take too literally!

# FACILITY CLOSURES AND PROJECT UPDATES



# Enabling works – tunnel, cooling building, roof

- Before B346A construction, we need to get rid of
  - B346K (black cooling building in parking lot)
  - Old tunnels in the way
- Establish
  - 4°C cooling water in B346 2<sup>nd</sup> floor for dehumidification
  - New tunnel north of B346A
- Impact
  - Power
  - Heat
  - Cooling water
  - CDA
- Schedule presently unknown – ca. Q3/Q4 2023
- Discussions with CAS and contractors ongoing
- Aim for “minimal impact” (but this is a big project)



# Decommissioning of equipment

- Nickel electroplating
- Polymer Injection machine
- Old Thickness Measurer (Wafer)
- Imprinter 02
- Inclined UV
- RTP Jipelec 1
- Wordentec (2024)

# SOI wafers on sale!

Advertisement

COMING FREE!  
SALE!

- Specs: And now a commercial break ...
  - Type: Silicon on Insulator;  $\varnothing$ 150 mm; <100>; DSP
  - Device layer: 60 +/- 1  $\mu$ m
  - BOX layer: 400 +/- 20 nm
  - Handle: 525 +/- 5  $\mu$ m
  - Doping: Phosphor. 1-20  $\Omega$ cm

Price:  
1000 DKK/wafer

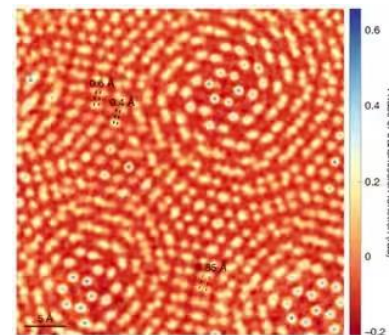
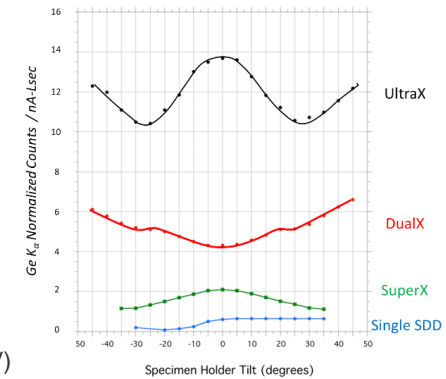
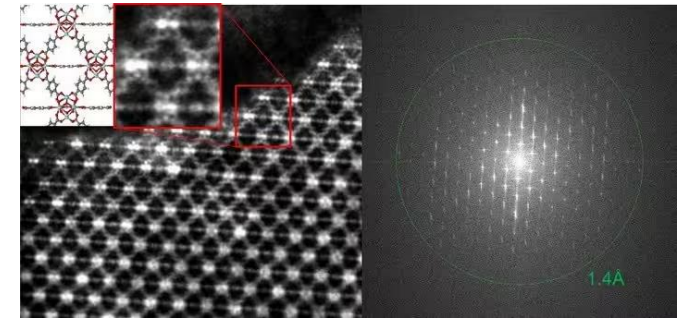
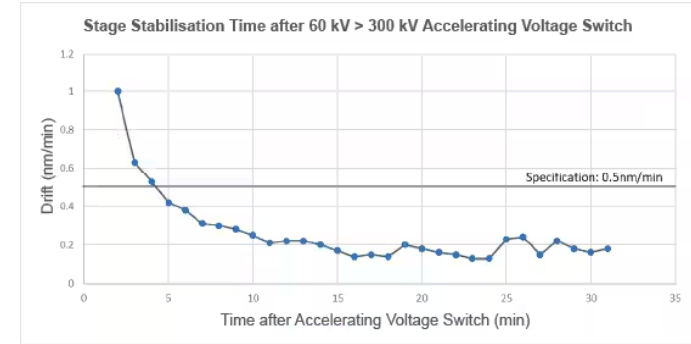
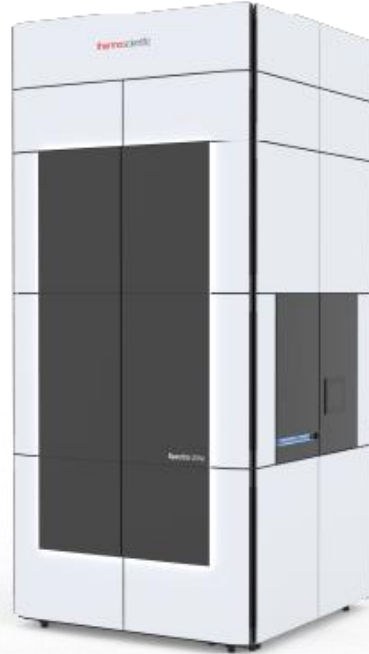
Contact [thope@dtu.dk](mailto:thope@dtu.dk) or [kabi@dtu.dk](mailto:kabi@dtu.dk) if you want to purchase.

SALE!

# NEW EQUIPMENT

# Spectra Ultra

- Probe and Image Cs correction
- 60kV, 120kV, 300kV (X-FEG)
- Ultra X-EDS detector (>4srad)
- Piezo-enhanced CompuStage
- Monochromator, OptiMono+
- Corrected TEM Lorentz mode
- Precession Diffraction
- EMPAD (Electron Microscope Pixelated Array Detector)
  - 128x128 direct electron detection
- 4D STEM, OptiSTEM+ (Panther segmented detector – iDPC)
- Ceta-S Camera (speed enhancement)
- GIF Continuum HR 1066
- Tomography Software



•Energy spread: 0.05 eV (0.025 eV @ 60kV)

•Information limit: <60 pm

•STEM resolution: <50 pm at 300kV >30pA of probe current  
 STEM resolution: <125pm at 30kV with >20pA of probe current

**Installation Q2+Q3 2023 in 314**

## Raith e-Line - smaller add on

- Laser height sensor installation
  - Automatic focusing
- Chuck for 6" wafers
  - field of view 100x100mm

### Need additional training:

[thope@dtu.dk](mailto:thope@dtu.dk) or [rawta@dtu.dk](mailto:rawta@dtu.dk)

- A vibration damping platform has been purchased (Q2 2023)



# MLA2 – upgraded from Write Mode 1 to Write Mode 2

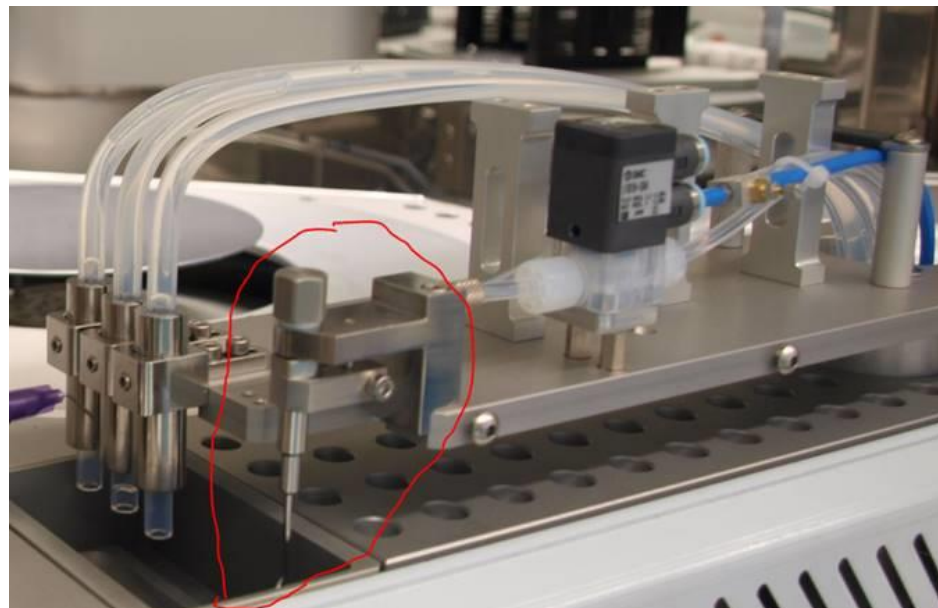
Has been changed from WM1 to WM2:

- A new write head is mounted
- All optics are changed
- The OAF adjusted to fit the new write head
  
- It is compatible with both wavelengths (375nm,405nm)
- It is compatible with both autofocus modes (optical/pneumatic)
- Small chip exposure is still possible
  
- High resolution option no longer an option
  - Resolution as MLA3 (>1  $\mu\text{m}$ )
- Faster writing speed ~ half the speed of MLA3
  
- To regain your authorization please contact:  
[jehem@dtu.dk](mailto:jehem@dtu.dk) or [Meenadh@dtu.dk](mailto:Meenadh@dtu.dk)



# Edge bead removal and backside rinse on Spin coater: Süss Stepper

- Issues with contamination on backside of wafers when spincoating
  - Issues with uniformity on some wafer types due to heat transfer from end effector to wafer
- Edge bead removal and backside rinse make it possible of spin coat all wafers first and then do the pre exposure baking afterwards without contaminating the tool

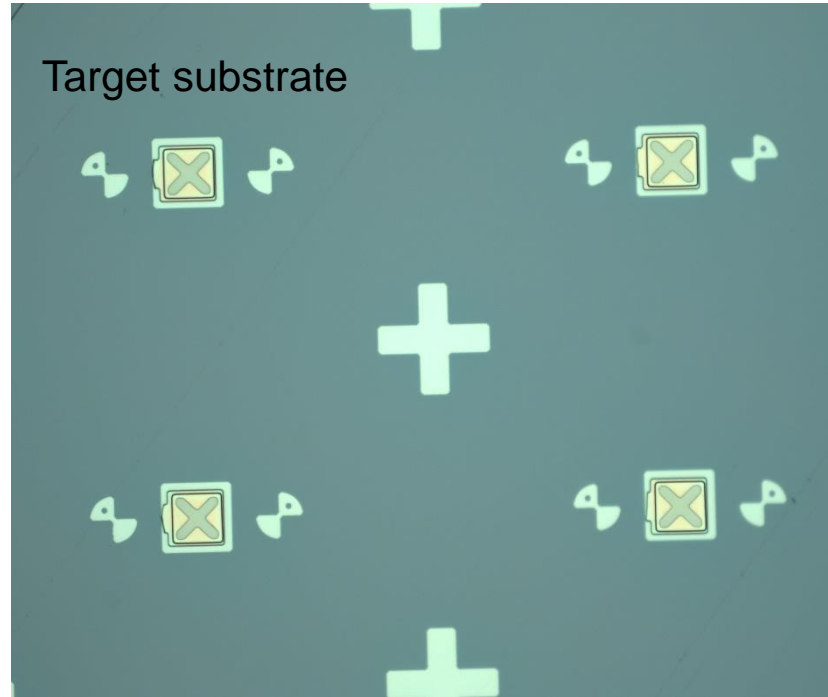
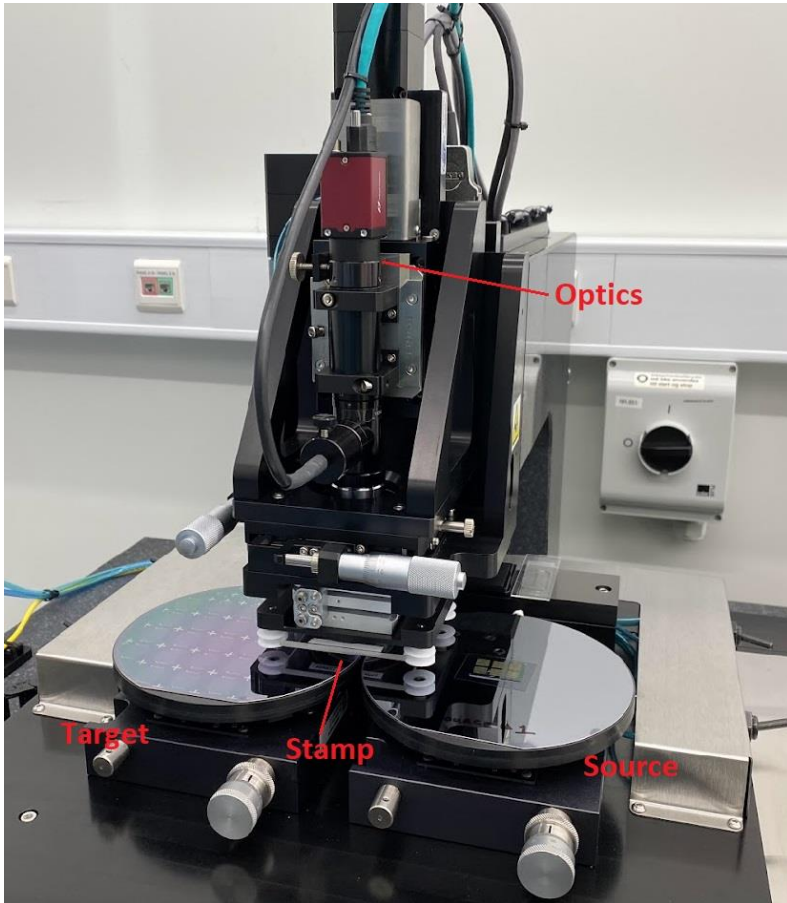


**EBR-needle will fit through existing nozzle holder**

**Solvent supply by existing TS1**



# μTransfer printing ready for use

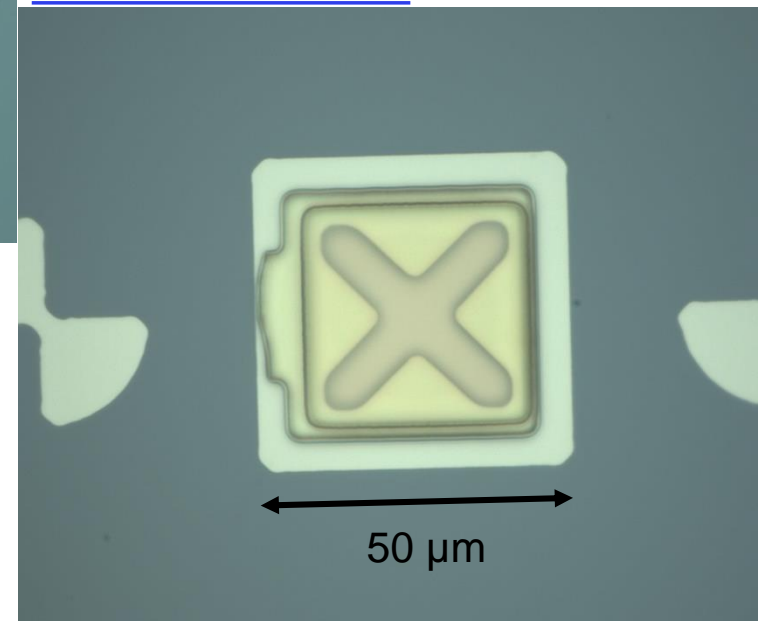


Simultaneous transfer of multiple coupons using elastomer stamp

Alignment accuracy within 1 μm

For training please contact:

[Meenadh@dtu.dk](mailto:Meenadh@dtu.dk)



Purchased in cooperation with DTU Electro



# Replacement of SU8 developer bench and Fumehood (RCA)

Delayed due to supply shortage of stainless steel



FAT expected to be in Autumn 2023

## Next SEM in 346



### GeminiSEM 560 from Carl Zeiss

- **Sophisticated in-column detectors:** The detectors have seen a lot of development since the Supra models. The column now hosts detectors with **energy-selective filtering** to reveal **subtle material contrasts** – from both secondary and backscattered electrons.
- **Greatly improved low vacuum modes: Local charge compensation** that enable the use of in-column detectors (usually reserved for high vacuum) of secondary and backscatter electrons thus dramatically **improving the imaging capabilities on non-conducting samples**
- **STEM detector**
- **Also: A variety of automated features, beam deceleration...**

**Expected delivery: Ultimo June 2023**

# Next E-Beam Evaporation System



## FC2000 from FerroTec-Temescal

### Features in general

- Robust & reliable system – easy maintenance
- High flexibility (substrate sizes)
- 10-pocket crucible
- High throughput - loadlock
- High-uniformity deposition
- Low sidewall deposition (for lift-off)

**Expected delivery: Ultimo May 2023**



# New Particle Scanner – Takano WM-7SR

- to replace our current KLA-Tencor Surfscan 6420

Special agreement with ClassOne/Takano:

- Demo-site for Takano
- 3 months trial period before decision (compare with Surfscan)
- Contract includes trade-in of Surfscan

| Major Specification            | WM-7S                      |
|--------------------------------|----------------------------|
| Wafer Size                     | 50mm~200mm                 |
| Sensitivity(Bare-Si)           | 0.079μm                    |
| Throughput                     | 55wph@200mm<br>60wph@150mm |
| Reproducibility $\sigma/x^-$   | 1.0% or less               |
| Dynamic Range                  | 0.079μm~5.0μm              |
| Coordinate Precision $3\sigma$ | 100μm or less              |





## Coming up – 2024

### X-Ray Diffractometer – outside the cleanroom

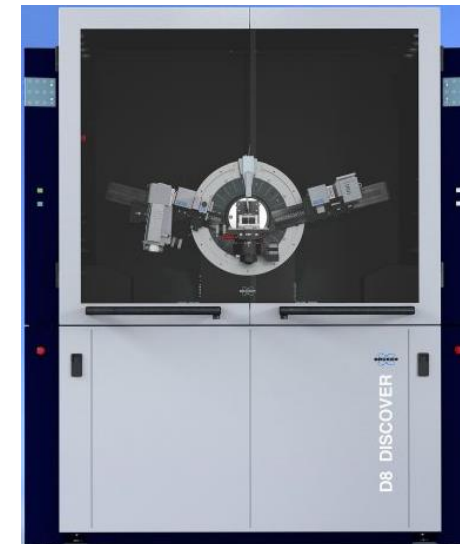
Material properties (crystalline/ poly/nano-crystalline):

- crystal orientation
- grain size
- electron density
- film thickness

Hardware improvement: Rotating anode source / 2D-detector ?

Visits at demo-sites with own samples (last week + ??)

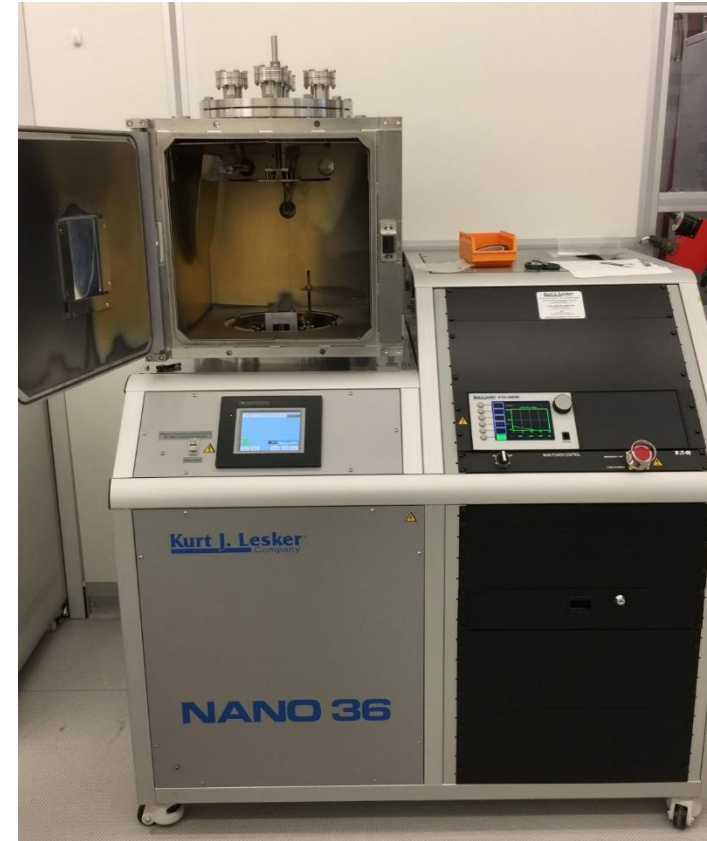
Tender process to be started



# Upgrade of Thermal Evaporator (KJL-NANO 36)

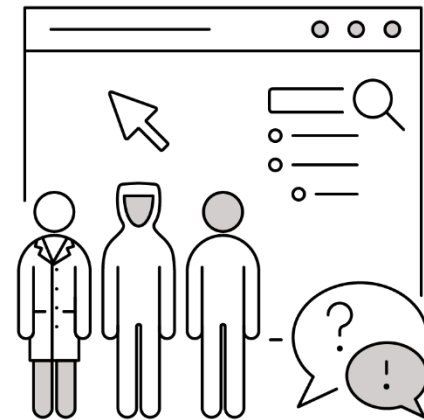
## Substrate rotation for improving uniformity

- preparation for end-of-life of Wordentec
- Expect installation 17 April 2023



# End of Presentation

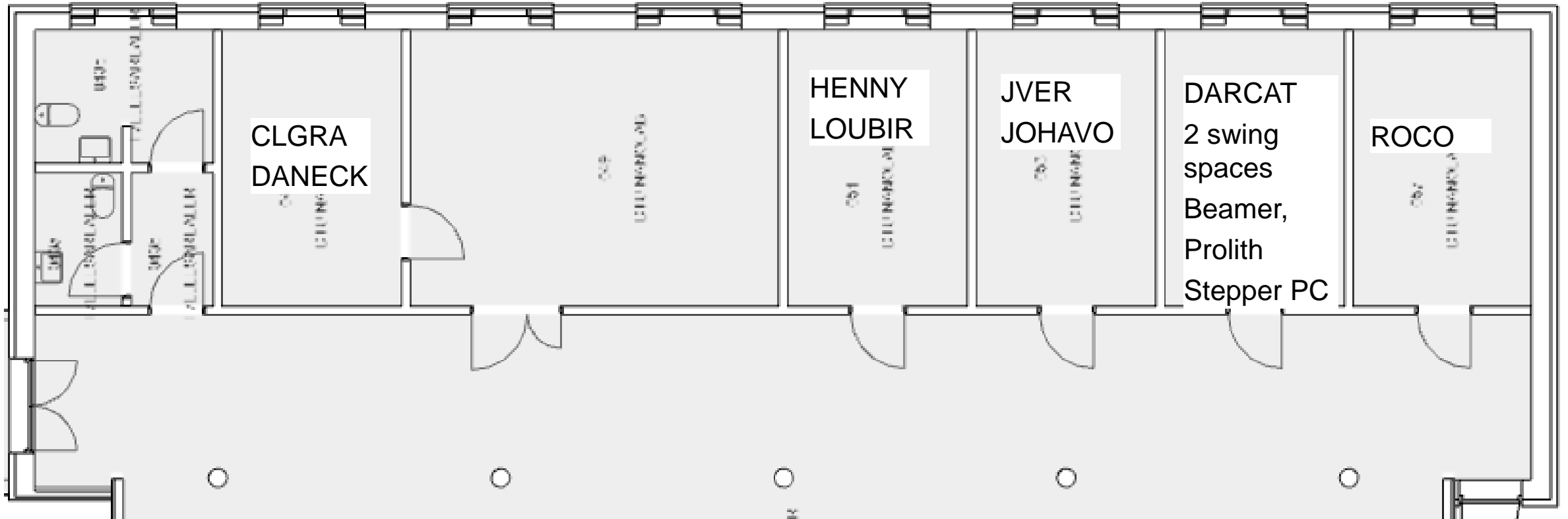
- DTU economical situation
- Building 347 incl. Packlab activities relocation
- Energy savings
- PolyFabLab
- Building 346A – Cleanroom Phase 4
- Possible interruptions due to 346A enabling works – tunnel work
- Decommissioning of old equipment
- New tools and upgrades of existing
- Slides will be available online





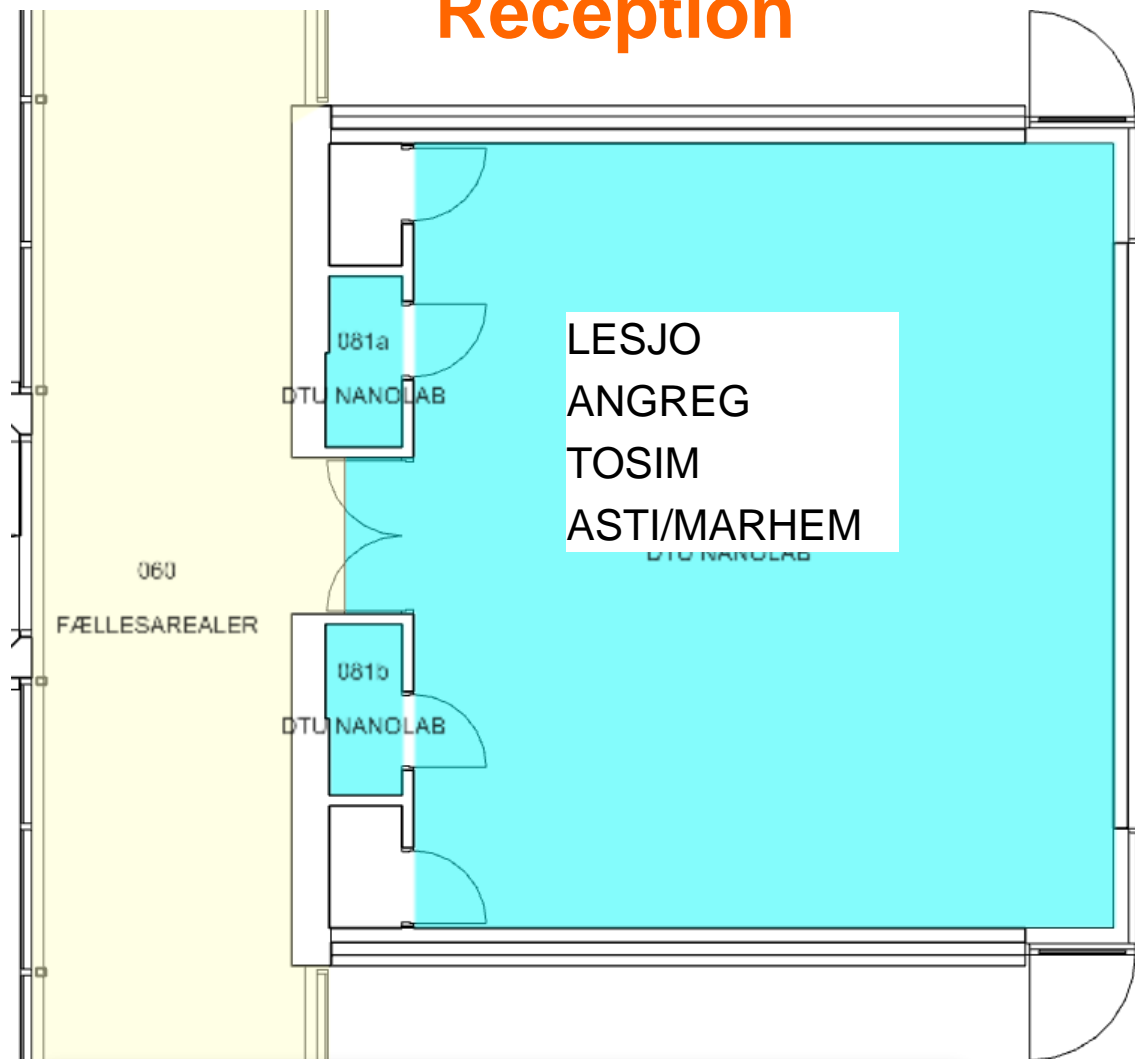
# B346 Offices

(Most of) Facility



# B347 Seminar Room

Reception



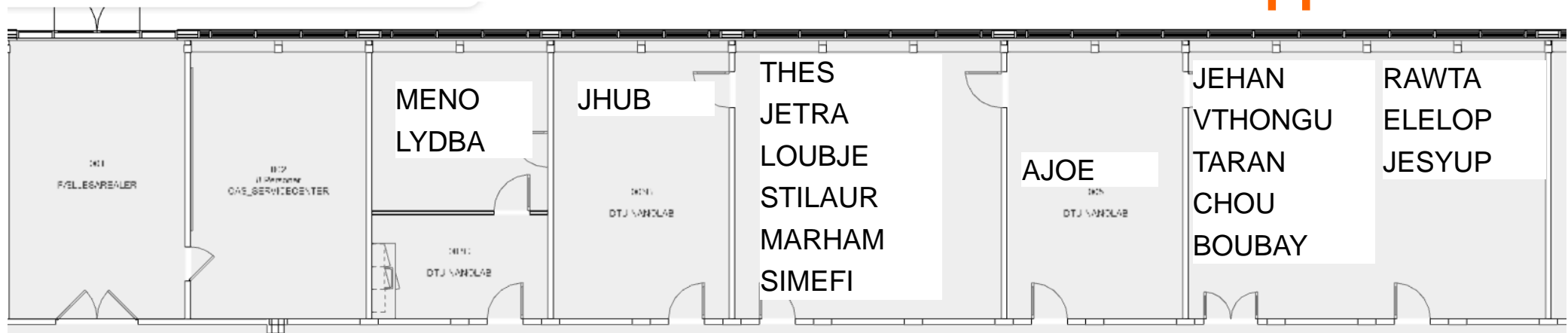
# B358 ground floor



Cleanroom

Akademivej

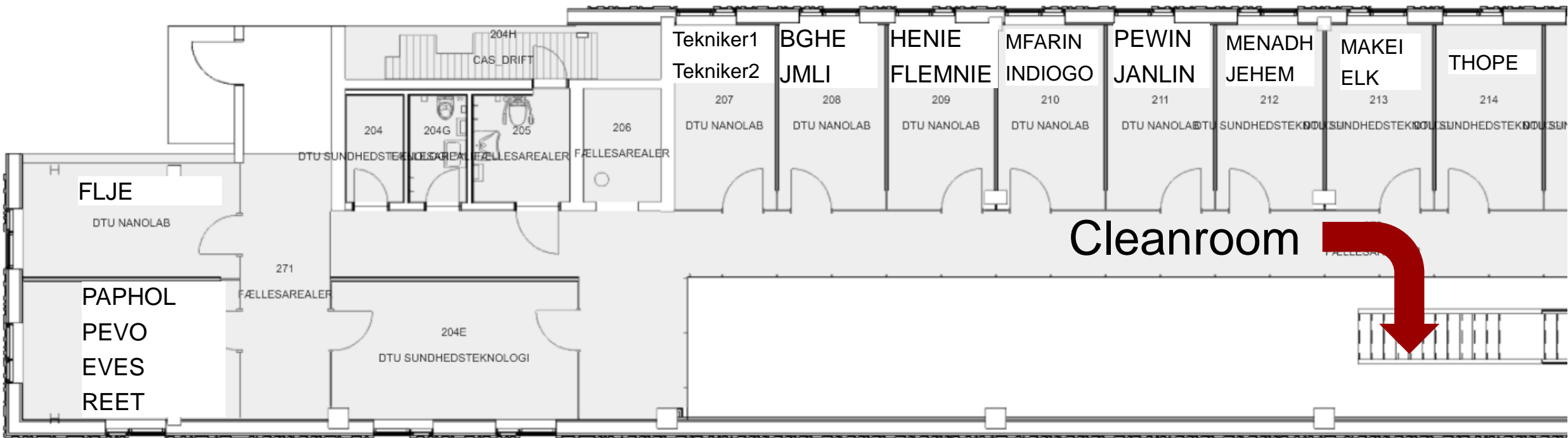
**Fabrication support**



# B345C 2<sup>nd</sup> floor

← Ørsted's Plads

## Thin Film & Dry Etch





# 345B ground floor

Cleanroom

Wet chemistry

